## **ACKNOWLEDGEMENT RECEIPT**

Electronic Version 1.1

Stylesheet Version v1.1.1

Title of Invention

## HIGH-PRESSURE PROCESSING CHAMBER FOR A SEMICONDUCTOR WAFER

Submision Type: Information Disclosure

Statement

**Application Number:** 

10/680783

EFS ID: 78047

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	Submission was successfully submitted - Even if Informational or Warning Messages appear below, please do not resubmit this application
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First Named Applicant: William Jones

Attorney Docket Number:

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File Listing:

Doc. Name	File Name	Size (Bytes)	Date
		` - /	Produced
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us-ids	SSI04001-usidst.xml	2843	2005-02-14
us-ids	us-ids.dtd	7763	2005-02-14
us-ids	us-ids.xsl	12026	2005-02-14
package-data	SSI04001-pkda.xml	1704	2005-02-14
package-data	package-data.dtd	27025	2005-02-14
package-data	us-package-data.xsl	19263	2005-02-14
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